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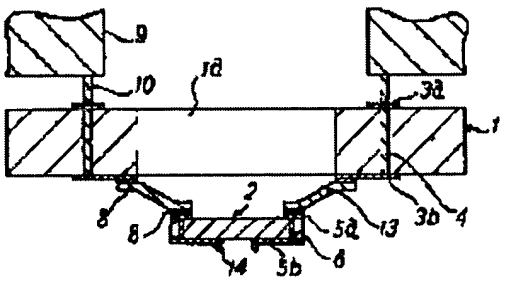
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(54) SEMICONDUCTOR INSPECTION APPARATUS

(57)Abstract:

PURPOSE: To obtain a semiconductor inspection apparatus wherein, irrespective of the parallelism of the surface of a semiconductor wafer to the surface of an inspection board, the good electric contact of an electrode pad on the semiconductor wafer with a bump electrode on the inspection board is ensured and the reliability of an inspection is increased.



CONSTITUTION: A plurality of wiring patterns 3a, 3b which have been connected electrically by a through hole 4 are formed on both faces of a probe card 1. A plurality of wiring patterns 5a, 5b which have been connected electrically by a through hole 6 are formed on both faces of an inspection board 2. The inspection board 2 is supported elastically by the probe card 1 in a state that the wiring pattern 5a has been connected electrically to the wiring pattern 3b by means of a tungsten wire 13. A bump electrode 14 which is provided with a sharp tip shape is formed at the end part of the wiring pattern 5b on the inspection board 2.

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